

1     ABSTRACT OF THE DISCLOSURE

2             A semiconductor processing workpiece support which includes a  
3     detection subsystem that detects whether a wafer or other workpiece is  
4     present. The preferred arrangement uses an optical beam emitter and  
5     an optical beam detector mounted along the back side of a rotor which  
6     acts as a workpiece holder. The emitted beam passes through the  
7     workpiece holder and is reflected by any workpiece present in the  
8     workpiece holder. The preferred units include both an optical emitter  
9     and pair of detectors. The detection is preferably able to discriminate  
10    on the basis of the angle of the reflected beam, so that a portion of  
11    the beam reflected by the workpiece holder is not considered or  
12    minimized.